

INFORMATION DISCLOSURE CITATION

Atty. Docket No.	04329.3161	Serial No.	Not Yet Assigned
Applicants	Kenji KAWANO et al.		
Filing Date	October 10, 2003	Group:	Not Yet Assigned

U.S. PATENT DOCUMENTS							
Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate	
Sbf	6,265,696	07/24/01	SAKURAI et al.				
	6,301,435	10/09/01	ITO et al.				
↓	6,333,493	12/25/01	SAKURAI et al.				
Sbf	6,550,990	04/22/03	SAKURAI et al.				

FOREIGN PATENT DOCUMENTS							
	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No	
Sbf	11-038644	02/12/99	JAPAN			ABSTRACT	
Sbf	2000-146444	05/26/00	JAPAN			ABSTRACT	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
Sbf	KAWANO, K. et al., "Apparatus For Processing Substrate and Method of Processing The Same", U.S. Patent Application No. 10/026,419, filed December 26, 2001.
Sbf	KIHARA, N. et al., "Effect of Acid Evaporation in Chemically Amplified Resists on Insoluble Layer Formation", Journal of Photopolymer Science and Technology, Vol. 8, No. 4, pp. 561-569, (1995).

Examiner <i>Shaontia Fugue</i>	Date Considered <i>4/11/05</i>
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce

INFORMATION DISCLOSURE CITATION

Atty. Docket No.	4329.3161	Appn. No.	10/682,419
Applicant	Kawano et al.	SEP 23 2004 U.S. PATENT AND TRADEMARK OFFICE	
Filing Date	October 10, 2003	Group:	2812

U.S. PATENT DOCUMENTS

Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

FOREIGN PATENT DOCUMENTS

		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
<i>Sgt</i>		2002-252167	9/6/02	Japan	—	—	
<i>Sgt</i>		6-124873	5/6/94	Japan	—	—	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner *Shawn Lai Seng* Date Considered *4/11/05*

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